


[Web](#) [Images](#) [Groups](#) [News](#) [Froogle](#) [Local](#) [more »](#)


[Advanced Search](#)  
[Preferences](#)

## Web

 Results 1 - 10 of about 50,700 for **particle size, laser beam, photodetector**. (0.22 seconds)

 Tip: Looking for pictures? Try [Google Images](#)
[Sponsored Links](#)

### Multiple Scattering Suppression in Laser Light Scattering

Older **laser**-light-scattering methods for determining **particle sizes** from cross- or autocorrelation of **photodetector** outputs entail various deficiencies and ...

[www.nasatech.com/Briefs/Nov99/LEW16517.html](http://www.nasatech.com/Briefs/Nov99/LEW16517.html) - 8k -

[Cached](#) - [Similar pages](#)

[PDF] [C:\Clientwork\...\TSI\\_verif.wp \[PFP#1010829998\]](#)

File Format: PDF/Adobe Acrobat - [View as HTML](#)

The avalanche **photodetector** then converts the light pulses into electrical pulses. Two partially overlapping **laser beams** allow each **particle** to generate a ...

[www.epa.gov/etv/pdfs/vrvs/01\\_vs\\_tsi\\_3320aps.pdf](http://www.epa.gov/etv/pdfs/vrvs/01_vs_tsi_3320aps.pdf) - [Similar pages](#)

### Optical / Photodetector

High-speed, low-cost, compact optical detector / **photodetector** module  
[www.lightility.com](http://www.lightility.com)

### Laser Detector?

Brief and Straightforward Guide to Radar Detectors  
[wisegeek.com](http://wisegeek.com)

### SOAR fleet

Light scattered by a **particle** entering the **laser beam** is collected and focused onto a ... The **particle sizing** data is updated at 1-second intervals. ...

[www.sandylandwater.com/research\\_aircraft.htm](http://www.sandylandwater.com/research_aircraft.htm) - 24k - [Cached](#) - [Similar pages](#)

### Dynamic Light Scattering | Ultrafine Particle Analyzer | PSA | PSD ...

... and returns the scattered and the reflected **beams** to the **photodetector**. ... **Particle Size Analyzer | Particle Size Distribution | PSA | PSD | Laser ...**

[www.microtrac.com/dynamicscattering.cfm](http://www.microtrac.com/dynamicscattering.cfm) - 28k - [Cached](#) - [Similar pages](#)

### [PDF] The Next Generation PDPA/LDV Systems

File Format: PDF/Adobe Acrobat

generates the **laser beams** needed for one-, two- or three-component PDPA/LDV systems. ... velocity and **particle size** fields. Details of flow and **particle** ...

[www.tsi.com/documents/PDPA.pdf](http://www.tsi.com/documents/PDPA.pdf) - [Similar pages](#)

### FSSP-300

A Helium Neon **laser beam** is focused to a small diameter at the center of an ... The **size** of the **particle** is determined by measuring the light scattering ...

[raf.atd.ucar.edu/Bulletins/B24/fssp300.html](http://raf.atd.ucar.edu/Bulletins/B24/fssp300.html) - 8k - [Cached](#) - [Similar pages](#)

### PCASP-100

A Helium Neon **laser beam** is focused to a small diameter at the center an ... DBARP Average Diameter Arithmetic average of **particle size** - micrometers ...

[raf.atd.ucar.edu/Bulletins/B24/pcasp100.html](http://raf.atd.ucar.edu/Bulletins/B24/pcasp100.html) - 6k - [Cached](#) - [Similar pages](#)

### Available equipment

Shadow images of cloud **particles** in a **size** range between 25 and 800  $\mu\text{m}$  are focused ... The distance along the **laserbeam**, where crossing **particles** produce a ...

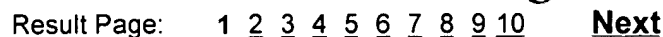
[w3.gkss.de/Pms/probes1.htm](http://w3.gkss.de/Pms/probes1.htm) - 16k - [Cached](#) - [Similar pages](#)







### [doc] Use of Particle Counters for measuring Water Treatment Plant ...

File Format: Microsoft Word 97 - [View as HTML](#)

Fluctuations in the light **beam** are measured by the **photodetector**. **Particles** in the sample

Cached - Similar pages



Google   Search   377 blocked  Check  AutoLink  AutoFill

particle size, laser beam, photodetector Search

[Search within results](#) | [Language Tools](#) | [Search Tips](#) | [Dissatisfied? Help us improve](#)

[Google Home](#) - [Advertising Programs](#) - [Business Solutions](#) - [About Google](#)

©2005 Google



Welcome United States Patent and Trademark Office

☐ Search Session History[BROWSE](#)[SEARCH](#)[IEEE XPLORE GUIDE](#)

Edit an existing query or  
compose a new query in the  
Search Query Display.

Mon, 12 Sep 2005, 5:40:10 PM EST

## Search Query Display

Select a search number (#)  
to:

- Add a query to the Search Query Display
- Combine search queries using AND, OR, or NOT
- Delete a search
- Run a search

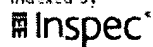
## Recent Search Queries

- #1 ((monitor size of a particle, laser beam, photodetector)  
<in>metadata)
- #2 ((monitor size of a particle, laser beam)<in>metadata)
- #3 ((particle size, laser beam, photodetector)<in>metadata)

[Help](#) [Contact Us](#) [Privacy &](#)

© Copyright 2005 IEEE -

Indexed by



Day : Monday  
Date: 9/12/2005


**PALM INTRANET**

Time: 17:07:44

**Inventor Name Search Result**

Your Search was:

Last Name = MORIYA

First Name = TSUYOSHI

Application#	Patent#	Status	Date Filed	Title	Inventor Name
<a href="#">09273293</a>	<a href="#">6306770</a>	150	03/19/1999	METHOD AND APPARATUS FOR PLASMA ETCHING	MORIYA, TSUYOSHI
<a href="#">09290636</a>	<a href="#">6184489</a>	150	04/12/1999	PARTICLE-REMOVING APPARATUS FOR A SEMICONDUCTOR DEVICE MANUFACTURING APPARATUS AND METHOD OF REMOVING PARTICLES	MORIYA, TSUYOSHI
<a href="#">09413590</a>	<a href="#">6115120</a>	150	10/06/1999	SYSTEM AND METHOD FOR DETECTING PARTICLES PRODUCED IN A PROCESS CHAMBER BY SCATTERING LIGHT	MORIYA, TSUYOSHI
<a href="#">09443050</a>	Not Issued	164	11/18/1999	PARTICLE DETECTION SYSTEM AND METHOD USING MONITORED OPERATING CONDITIONS OF A PROCESS CHAMBER	MORIYA, TSUYOSHI
<a href="#">09651186</a>	<a href="#">6346425</a>	150	08/30/2000	Vapor-phase processing method capable of eliminating particle formation	MORIYA, TSUYOSHI
<a href="#">09656713</a>	Not Issued	71	09/07/2000	Apparatus for monitoring particles and method of doing the same	MORIYA, TSUYOSHI
<a href="#">09685351</a>	<a href="#">6423176</a>	150	10/10/2000	PARTICLE-REMOVING APPARATUS FOR A SEMICONDUCTOR DEVICE MANUFACTURING APPARATUS AND METHOD OF REMOVING PARTICLES	MORIYA, TSUYOSHI
<a href="#">09721703</a>	<a href="#">6737666</a>	150	11/27/2000	APPARATUS AND METHOD FOR DETECTING AN END POINT OF A CLEANING PROCESS	MORIYA, TSUYOSHI

<u>09767960</u>	Not Issued	161	01/24/2001	Dust particle removing method and apparatus, impurity detecting method and system	MORIYA, TSUYOSHI
<u>09950759</u>	Not Issued	161	09/13/2001	Semiconductor fabrication device and method for preventing the attachment of extraneous particles	MORIYA, TSUYOSHI
<u>09962169</u>	Not Issued	161	09/24/2001	Semiconductor device manufacturing apparatus and method for manufacturing a semiconductor device	MORIYA, TSUYOSHI
<u>09971463</u>	Not Issued	83	10/05/2001	Particle-removing apparatus for a semiconductor device manufacturing apparatus and method of removing particles	MORIYA, TSUYOSHI
<u>10166303</u>	Not Issued	71	06/11/2002	Method of manufacturing semiconductor devices and semiconductor manufacturing apparatus	MORIYA, TSUYOSHI
<u>10722602</u>	Not Issued	30	11/28/2003	Internal member of a plasma processing vessel	MORIYA, TSUYOSHI
<u>10773245</u>	Not Issued	30	02/09/2004	Plasma processing apparatus, ring member and plasma processing method	MORIYA, TSUYOSHI
<u>10858049</u>	Not Issued	30	06/02/2004	Substrate processing apparatus and substrate transferring method	MORIYA, TSUYOSHI
<u>10920367</u>	Not Issued	30	08/18/2004	Particle removal apparatus and method and plasma processing apparatus	MORIYA, TSUYOSHI
<u>10921947</u>	Not Issued	30	08/20/2004	Method for cleaning elements in vacuum chamber and apparatus for processing substrates	MORIYA, TSUYOSHI
<u>10959197</u>	Not Issued	30	10/07/2004	Particle sticking prevention apparatus and plasma processing apparatus	MORIYA, TSUYOSHI
<u>11065359</u>	Not Issued	20	02/25/2005	Processing apparatus and method for removing particles therefrom	MORIYA, TSUYOSHI
<u>11091416</u>	Not Issued	20	03/29/2005	Plasma processing apparatus and method	MORIYA, TSUYOSHI
<u>11091417</u>	Not Issued	20	03/29/2005	Vacuum apparatus including a particle monitoring unit, particle monitoring method and program, and window member for use in the particle monitoring	MORIYA, TSUYOSHI

<u>11115357</u>	Not Issued	19	04/27/2005	Substrate transfer device and cleaning method thereof and substrate processing system and cleaning method thereof	MORIYA, TSUYOSHI
<u>11115358</u>	Not Issued	30	04/27/2005	Substrate cleaning apparatus and method	MORIYA, TSUYOSHI
<u>11128256</u>	Not Issued	20	05/13/2005	Substrate transfer mechanism and substrate transfer apparatus including same, particle removal method for the substrate transfer mechanism and apparatus, program for executing the method, and storage medium for storing the program	MORIYA, TSUYOSHI
<u>11171236</u>	Not Issued	20	07/01/2005	Apparatus for inspecting a surface of an object to be processed	MORIYA, TSUYOSHI
<u>60589807</u>	Not Issued	159	07/22/2004	Transfer apparatus and processing system of workpieces and method thereof	MORIYA, TSUYOSHI
<u>60589808</u>	Not Issued	159	07/22/2004	Method and apparatus for cleaning workpieces	MORIYA, TSUYOSHI
<u>60589810</u>	Not Issued	159	07/22/2004	Particle monitor and processing system with particle monitor	MORIYA, TSUYOSHI
<u>60598425</u>	Not Issued	159	08/04/2004	Apparatus for inspecting surface of workpiece	MORIYA, TSUYOSHI
<u>60626467</u>	Not Issued	20	11/10/2004	Apparatus for plasma processing, and method, computer program and recording medium	MORIYA, TSUYOSHI
<u>60635615</u>	Not Issued	20	12/14/2004	Method, apparatus, computer program and recording medium for cleaning substrate, and system for processing substrate	MORIYA, TSUYOSHI
<u>60635617</u>	Not Issued	20	12/14/2004	Vacuum apparatus, method for particle monitor thereof, computer program for the method and window member for particle monitor	MORIYA, TSUYOSHI
<u>60635942</u>	Not Issued	20	12/15/2004	System and apparatus for transferring substrate, method for removing particle thereof, computer program for the method and recording medium for the computer program	MORIYA, TSUYOSHI
<u>60635945</u>	Not Issued	20	12/15/2004	Controlling method for substrate-processing apparatus, substrate-	MORIYA, TSUYOSHI

				processing apparatus, computer program for the method	
<u>60635968</u>	Not Issued	20	12/15/2004	Member for substrate processing apparatus and method for making the same	MORIYA, TSUYOSHI
<u>60635970</u>	Not Issued	20	12/15/2004	Ceramic-sprayed member, method for cleaning the same, computer program for the method and recording medium for the computer program	MORIYA, TSUYOSHI
<u>60650956</u>	Not Issued	20	02/09/2005	Cleaning method of processing apparatus, computer program for performing the method, and recording medium for storing the program	MORIYA, TSUYOSHI
<u>60662794</u>	Not Issued	20	03/18/2005	Member for introducing gas and plasma processing apparatus using the same	MORIYA, TSUYOSHI
<u>60663187</u>	Not Issued	20	03/21/2005	Reflection device, manifold and vacuum pump for exhausting gas, and exhaust system therewith	MORIYA, TSUYOSHI
<u>60666703</u>	Not Issued	20	03/31/2005	Atmospheric transfer module	MORIYA, TSUYOSHI
<u>60666717</u>	Not Issued	20	03/31/2005	Method of removing moisture from vacuum vessel, computer program of executing the method and storage medium of the program	MORIYA, TSUYOSHI
<u>08680863</u>	<u>5889596</u>	150	07/16/1996	CONTROLLING A READING UNIT OF AN IMAGE PROCESSING APPARATUS	MORIYAMA, TSUYOSHI
<u>08843271</u>	<u>6094510</u>	150	04/14/1997	IMAGE PROCESSING APPARATUS AND METHOD FOR PREDICTING A COMPRESSION RATE OF IMAGE DATA PROCESSED TO MODIFY AN IMAGE	MORIYAMA, TSUYOSHI
<u>09092091</u>	<u>6413884</u>	150	06/05/1998	METHOD OF PRODUCING THIN FILMS USING CURRENT OF PROCESS GAS AND INERT GAS COLLIDING WITH EACH OTHER	MORIYAMA, TSUYOSHI
<u>09261955</u>	<u>6337970</u>	150	03/03/1999	IMAGE FORMING APPARATUS HAVING SHEET PROCESSOR	MORIYAMA, TSUYOSHI
<u>09282489</u>	<u>6391116</u>	150	03/31/1999	SEMICONDUCTOR DEVICE	MORIYAMA,

				MANUFACTURING APPARATUS AND SEMICONDUCTOR DEVICE MANUFACTURING METHOD	TSUYOSHI
<a href="#">09418590</a>	<a href="#">6263173</a>	150	10/15/1999	Image formation apparatus having selection of different image types for image formation	MORIYAMA, TSUYOSHI
<a href="#">09438525</a>	<a href="#">6219503</a>	150	11/12/1999	SHEET PROCESSING APPARATUS AND METHOD WITH MULTI-MODE SHEET CONVEYING	MORIYAMA, TSUYOSHI
<a href="#">09438527</a>	<a href="#">6386080</a>	150	11/12/1999	SHEET PROCESSOR THAT ADJUSTS A PUNCHING OPERATION POSITION BASED ON A DETECTED SHEET EDGE AND ASSOCIATED IMAGE FORMING APPARATUS	MORIYAMA, TSUYOSHI

[Search and Display More Records.](#)

**Search Another: Inventor**

Last Name	First Name
<input type="text" value="MORIYA"/>	<input type="text" value="TSUYOSHI"/>

To go back use Back button on your browser toolbar.

Back to [PALM](#) | [ASSIGNMENT](#) | [OASIS](#) | [Home page](#)

Day : Monday  
Date: 9/12/2005

PALM INTRANET

Time: 17:22:40

**Inventor Name Search Result**

Your Search was:

Last Name = ITO

First Name = NATSUOKO

Application#	Patent#	Status	Date Filed	Title	Inventor Name
<a href="#">08252656</a>	Not Issued	161	06/01/1994	ACCELERATION SENSOR	ITO, NATSUOKO
<a href="#">08541266</a>	<a href="#">5747991</a>	150	10/12/1995	CAPACITANCE TYPE ACCELERATION SENSOR	ITO, NATSUOKO
<a href="#">08837942</a>	<a href="#">5870189</a>	150	04/28/1997	PARTICLE MONITOR AND PARTICLE-FREE RECESSING SYSTEM WITH PARTICLE MONITOR	ITO, NATSUOKO
<a href="#">08989630</a>	<a href="#">5861951</a>	150	12/12/1997	PARTICLE MONITORING INSTRUMENT	ITO, NATSUOKO
<a href="#">09070750</a>	<a href="#">6042650</a>	150	05/01/1998	PROCESSING APPARATUS FOR FABRICATING LSI WITH PROTECTED BEAM DAMPER	ITO, NATSUOKO
<a href="#">09273293</a>	<a href="#">6306770</a>	150	03/19/1999	METHOD AND APPARATUS FOR PLASMA ETCHING	ITO, NATSUOKO
<a href="#">09290636</a>	<a href="#">6184489</a>	150	04/12/1999	PARTICLE-REMOVING APPARATUS FOR A SEMICONDUCTOR DEVICE MANUFACTURING APPARATUS AND METHOD OF REMOVING PARTICLES	ITO, NATSUOKO
<a href="#">09413590</a>	<a href="#">6115120</a>	150	10/06/1999	SYSTEM AND METHOD FOR DETECTING PARTICLES PRODUCED IN A PROCESS CHAMBER BY SCATTERING LIGHT	ITO, NATSUOKO
<a href="#">09443050</a>	Not Issued	164	11/18/1999	PARTICLE DETECTION SYSTEM AND METHOD USING MONITORED OPERATING CONDITIONS OF A PROCESS CHAMBER	ITO, NATSUOKO
<a href="#">09504435</a>	<a href="#">6284049</a>	150	02/15/2000	Processing APPARATUS FOR FABRICATING LSI DEVICES	ITO, NATSUOKO

<a href="#">09651186</a>	<a href="#">6346425</a>	150	08/30/2000	Vapor-phase processing method capable of eliminating particle formation	ITO, NATSUKE
<a href="#">09656713</a>	Not Issued	71	09/07/2000	Apparatus for monitoring particles and method of doing the same	ITO, NATSUKE
<a href="#">09685351</a>	<a href="#">6423176</a>	150	10/10/2000	PARTICLE-REMOVING APPARATUS FOR A SEMICONDUCTOR DEVICE MANUFACTURING APPARATUS AND METHOD OF REMOVING PARTICLES	ITO, NATSUKE
<a href="#">09721703</a>	<a href="#">6737666</a>	150	11/27/2000	APPARATUS AND METHOD FOR DETECTING AN END POINT OF A CLEANING PROCESS	ITO, NATSUKE
<a href="#">09767960</a>	Not Issued	161	01/24/2001	Dust particle removing method and apparatus, impurity detecting method and system	ITO, NATSUKE
<a href="#">09950759</a>	Not Issued	161	09/13/2001	Semiconductor fabrication device and method for preventing the attachment of extraneous particles	ITO, NATSUKE
<a href="#">09962169</a>	Not Issued	161	09/24/2001	Semiconductor device manufacturing apparatus and method for manufacturing a semiconductor device	ITO, NATSUKE
<a href="#">09971463</a>	Not Issued	83	10/05/2001	Particle-removing apparatus for a semiconductor device manufacturing apparatus and method of removing particles	ITO, NATSUKE
<a href="#">10166303</a>	Not Issued	71	06/11/2002	Method of manufacturing semiconductor devices and semiconductor manufacturing apparatus	ITO, NATSUKE
<a href="#">09236593</a>	Not Issued	161	01/26/1999	PHARMACEUTICAL COMPOSITIONS FOR THE TREATMENT OF ISCHEMIC BRAIN DAMAGE	ITO, NATSUKE

Inventor Search Completed: No Records to Display.

Search Another: Inventor

To go back use Back button on your browser toolbar.

Back to [PALM](#) | [ASSIGNMENT](#) | [OASIS](#) | [Home page](#)

Day : Monday  
Date: 9/12/2005

**PALM INTRANET**

Time: 17:12:25

## Inventor Name Search Result

Your Search was:

Last Name = UESUGI

First Name = FUMIHIKO

Application#	Patent#	Status	Date Filed	Title	Inventor Name
<a href="#">07123460</a>	<a href="#">4873413</a>	150	11/20/1987	METHOD AND APPARATUS FOR WRITING A LINE ON A PATTERNED SUBSTRATE	UESUGI, FUMIHIKO
<a href="#">07717603</a>	<a href="#">5393577</a>	150	06/19/1991	METHOD FOR FORMING A PATTERNED LAYER BY SELECTIVE CHEMICAL VAPOR DEPOSITION	UESUGI, FUMIHIKO
<a href="#">08837942</a>	<a href="#">5870189</a>	150	04/28/1997	PARTICLE MONITOR AND PARTICLE-FREE RECESSING SYSTEM WITH PARTICLE MONITOR	UESUGI, FUMIHIKO
<a href="#">08989630</a>	<a href="#">5861951</a>	150	12/12/1997	PARTICLE MONITORING INSTRUMENT	UESUGI, FUMIHIKO
<a href="#">09070750</a>	<a href="#">6042650</a>	150	05/01/1998	PROCESSING APPARATUS FOR FABRICATING LSI WITH PROTECTED BEAM DAMPER	UESUGI, FUMIHIKO
<a href="#">09273293</a>	<a href="#">6306770</a>	150	03/19/1999	METHOD AND APPARATUS FOR PLASMA ETCHING	UESUGI, FUMIHIKO
<a href="#">09290636</a>	<a href="#">6184489</a>	150	04/12/1999	PARTICLE-REMOVING APPARATUS FOR A SEMICONDUCTOR DEVICE MANUFACTURING APPARATUS AND METHOD OF REMOVING PARTICLES	UESUGI, FUMIHIKO
<a href="#">09413590</a>	<a href="#">6115120</a>	150	10/06/1999	SYSTEM AND METHOD FOR DETECTING PARTICLES PRODUCED IN A PROCESS CHAMBER BY SCATTERING LIGHT	UESUGI, FUMIHIKO
<a href="#">09443050</a>	Not Issued	164	11/18/1999	PARTICLE DETECTION SYSTEM AND METHOD USING MONITORED OPERATING CONDITIONS OF A PROCESS CHAMBER	UESUGI, FUMIHIKO

<a href="#">09504435</a>	<a href="#">6284049</a>	150	02/15/2000	Processing APPARATUS FOR FABRICATING LSI DEVICES	UESUGI, FUMIHIKO
<a href="#">09656713</a>	Not Issued	71	09/07/2000	Apparatus for monitoring particles and method of doing the same	UESUGI, FUMIHIKO
<a href="#">09685351</a>	<a href="#">6423176</a>	150	10/10/2000	PARTICLE-REMOVING APPARATUS FOR A SEMICONDUCTOR DEVICE MANUFACTURING APPARATUS AND METHOD OF REMOVING PARTICLES	UESUGI, FUMIHIKO
<a href="#">09721703</a>	<a href="#">6737666</a>	150	11/27/2000	APPARATUS AND METHOD FOR DETECTING AN END POINT OF A CLEANING PROCESS	UESUGI, FUMIHIKO
<a href="#">09767960</a>	Not Issued	161	01/24/2001	Dust particle removing method and apparatus, impurity detecting method and system	UESUGI, FUMIHIKO
<a href="#">09950759</a>	Not Issued	161	09/13/2001	Semiconductor fabrication device and method for preventing the attachment of extraneous particles	UESUGI, FUMIHIKO
<a href="#">09962169</a>	Not Issued	161	09/24/2001	Semiconductor device manufacturing apparatus and method for manufacturing a semiconductor device	UESUGI, FUMIHIKO
<a href="#">09971463</a>	Not Issued	83	10/05/2001	Particle-removing apparatus for a semiconductor device manufacturing apparatus and method of removing particles	UESUGI, FUMIHIKO
<a href="#">10166303</a>	Not Issued	71	06/11/2002	Method of manufacturing semiconductor devices and semiconductor manufacturing apparatus	UESUGI, FUMIHIKO

Inventor Search Completed: No Records to Display.

Search Another: Inventor

To go back use Back button on your browser toolbar.

Back to [PALM](#) | [ASSIGNMENT](#) | [OASIS](#) | Home page